

TRENDS IN LEVENSDUURTESTEN VOOR MICRO-ELEKTRONICA

PLOT CONFERENTIE

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8 JUNI 2016

MICROELECTRONICS RELIABILITY 54 (2014) 1988–1994



EXTERNAL USE

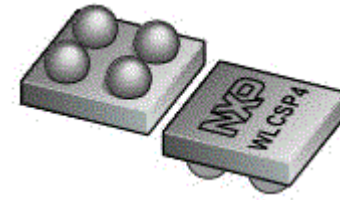


SECURE CONNECTIONS
FOR A SMARTER WORLD

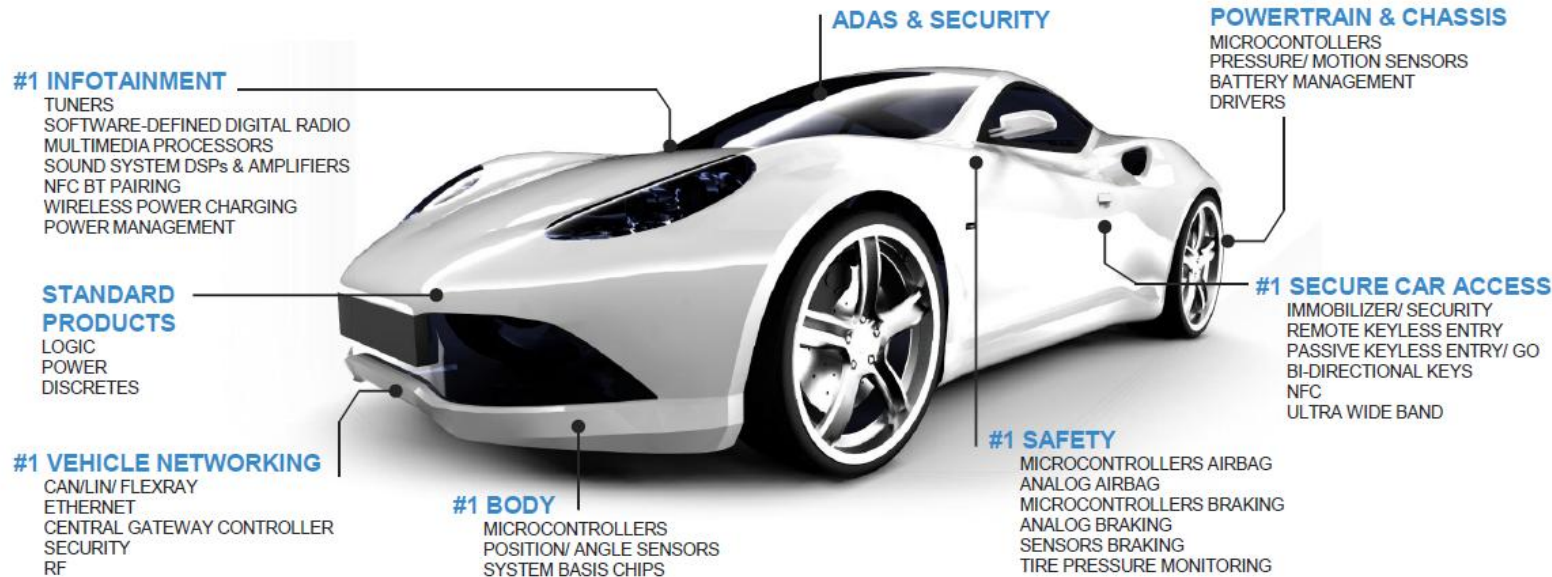
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Introduction NXP



TODAY: 90% OF AUTO INNOVATION VIA ELECTRONICS
NXP IS #1

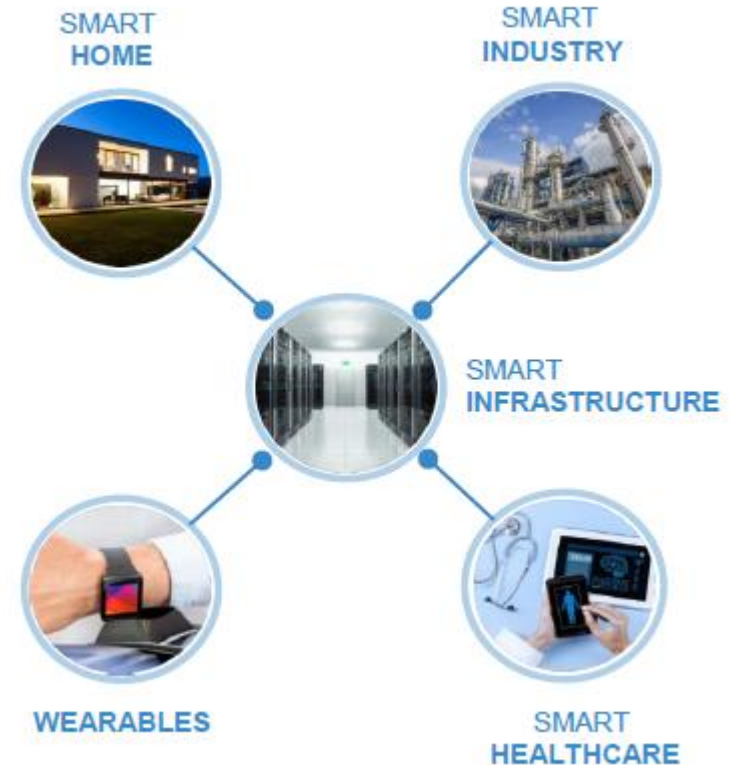


#1 Auto Analog/ RF

#1 Auto MCU (ex JPN)

#1 Auto Merchant MEMS Sensors

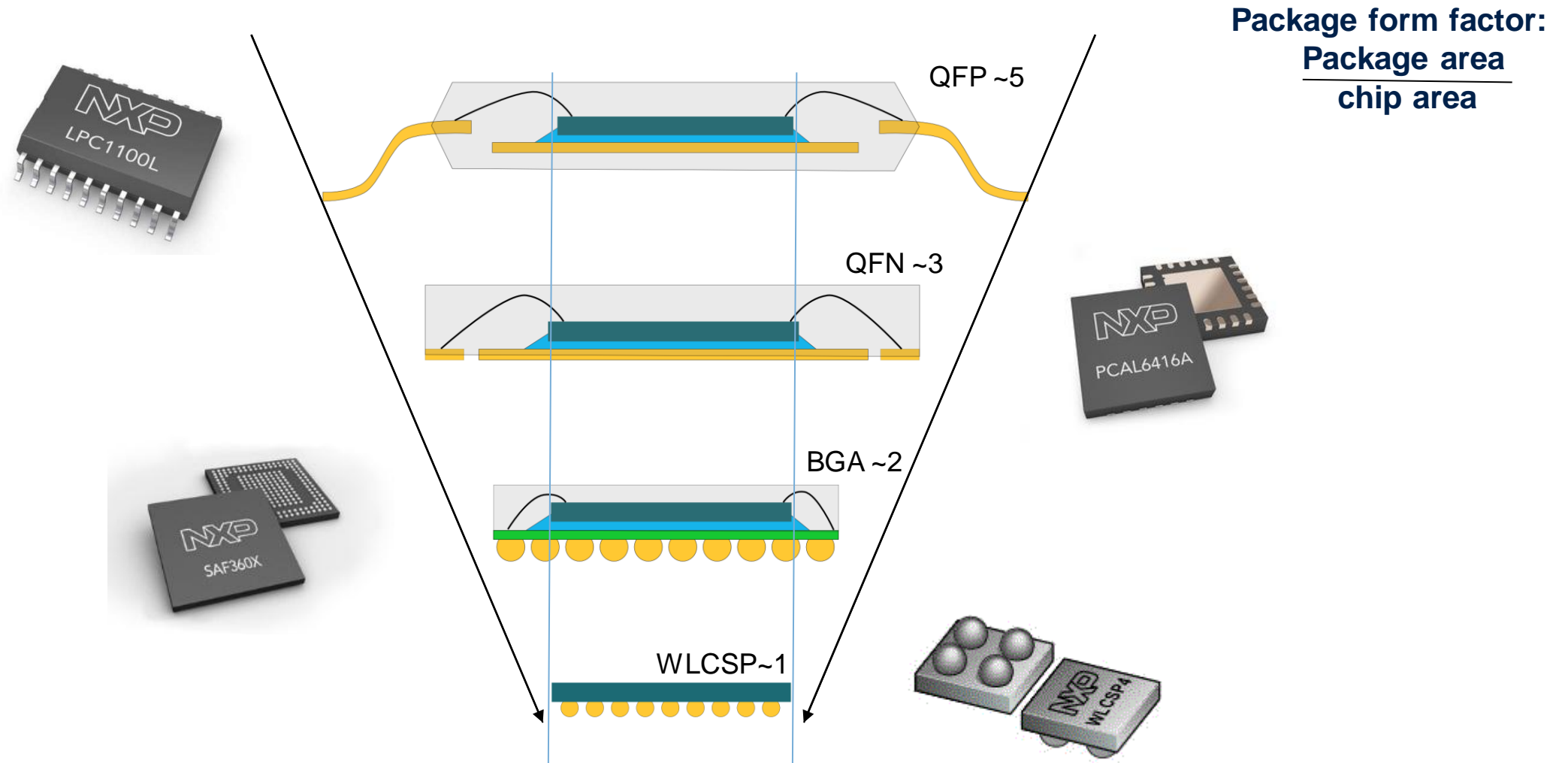
Smart Connected



Introduction NXP



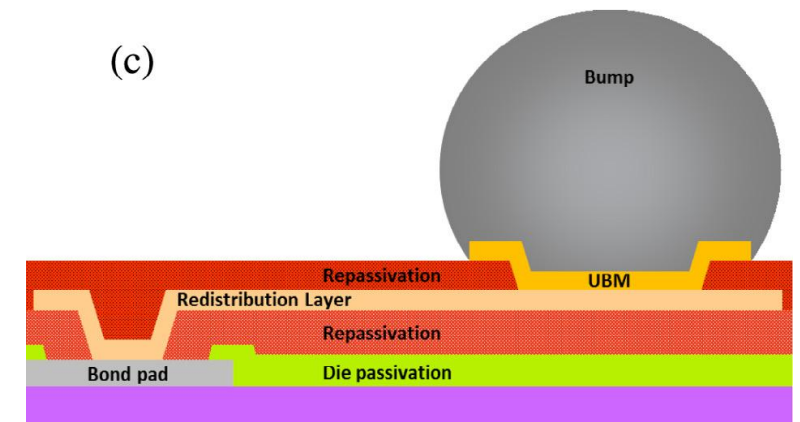
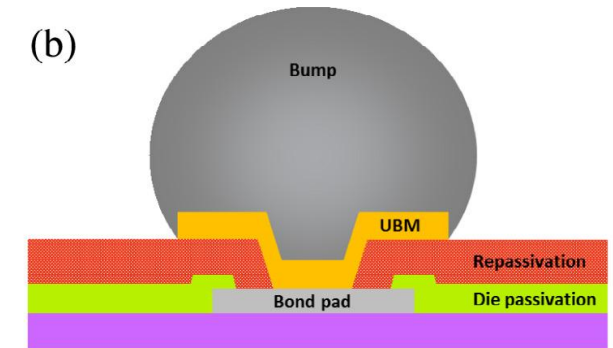
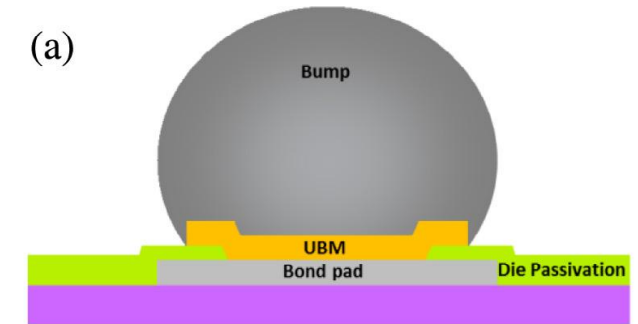
Package Form Factor



WLCSP bump construction

Predominant types of WLCSP bump constructions

- (A) Direct bumping
 - Under bump metallization (UBM) is directly on the chip's bond pad
- (B) Repassivation
 - A repassivation layer is applied before UBM and bump
 - Decoupling of chip and package
- (C) Redistribution
 - Allows for rerouting of electrical contact.
 - Allows to bump chips used in wire bond packages
 - Fan-in and Fan-out constructions



Failure mechanism driven qualification

- Technologies for semiconductor components are evolving rapidly:
 - Reduced dimensions (e.g., 22 nm wafer fab technology, CSP assembly)
 - More complex (e.g., 3D packages, Package on Package)
 - New devices (e.g., MEMS, CMOS sensors)
- Qualifying products by fulfilling a standard list of tests with prescribed conditions, duration and sample sizes without fails will not be appropriate anymore.
- A risk assessment on relevant failure modes (FMEA) is needed to construct a reliability risk mitigation plan.

Failure mechanism driven qualification

- The use conditions of a device in an application are typically characterized by a Mission Profile (MP)
- Typical elements in a mission profile are for example (but not limited to):
 - Expected field lifetime
 - Temperatures and duration typical for operating the device in the application
 - Environmental stress (thermo-mechanical loading, humidity)

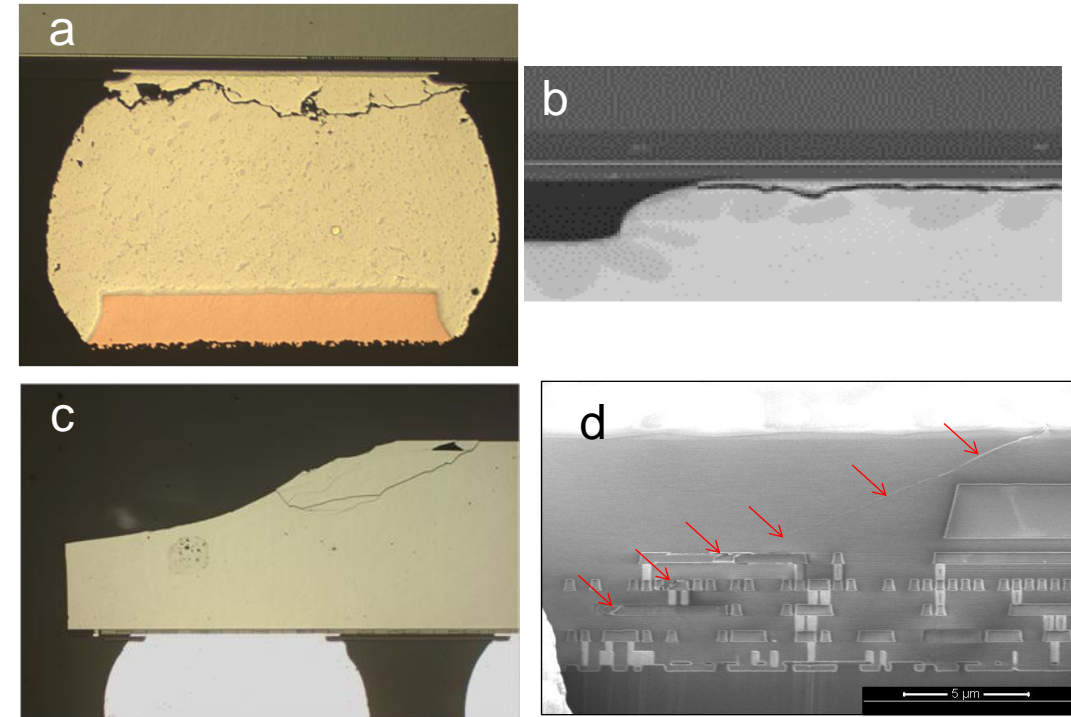
Example of the Mission Profile (MP) for a tablet/smart phone.

Field life time: 5 years		
Operation mode	H/day	$T_{\text{device}} (^{\circ}\text{C})$
Power	8	85
Sleep	8	25
Idle	8	60
Cycle mode	Cls/day	$\Delta T (^{\circ}\text{C})$
Power off ↔ on	1	75
Sleep ↔ idle	10	35
Idle ↔ power	3	25

(Thermo) Mechanical Failure Modes

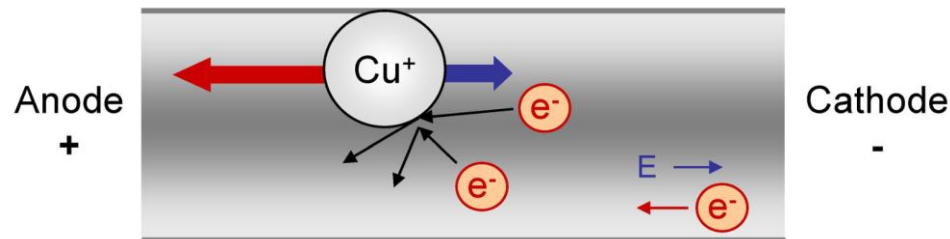
Four modes: symptom and occurrence

- a) Fatigue crack, through the solder bump at the die/silicon side, observed after temperature cycling
- b) Brittle fracture, through the solder bump at the die/silicon side, observed after (cyclic) drop or vibration events
- c) Chip out, observed directly, after manufacturing or as early field life fail
- d) Brittle fracture in the passivation (top) layer, even extending into the BEoL, after temperature cycling

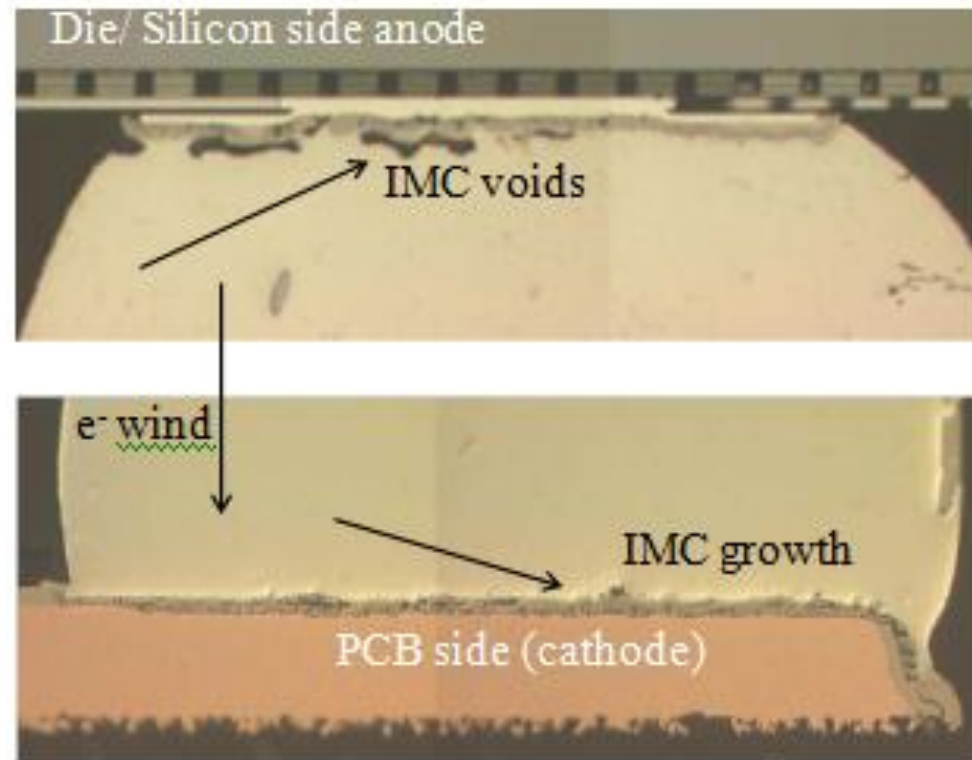


Current Driven Failure Modes

- Electromigration, in case a high current is running through the bump
- Void growing upstream the e-wind, as a result of extensive exposure to high temperature and current

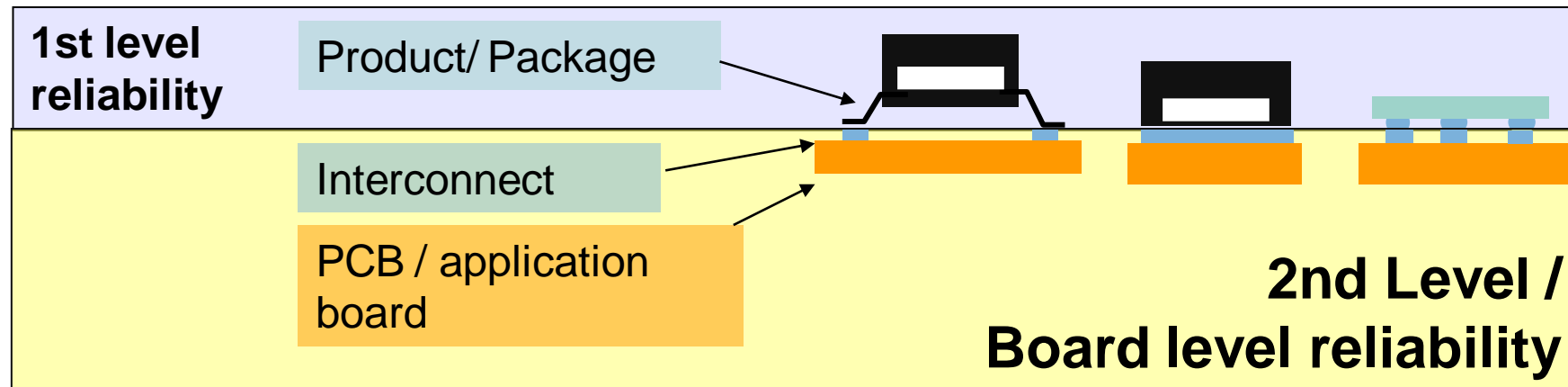


wikipedia



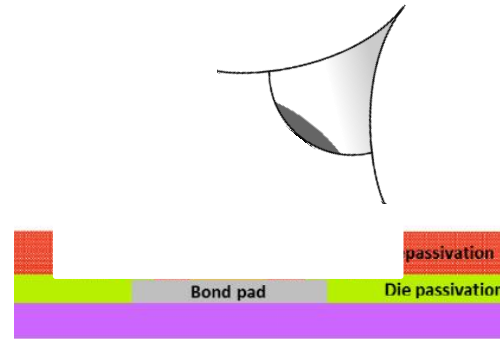
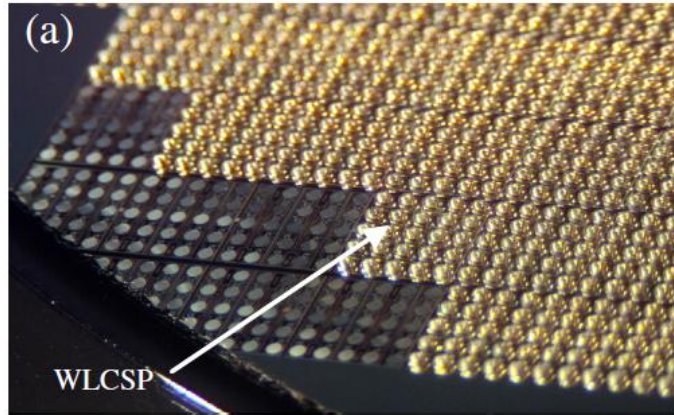
First and second level reliability

- First level reliability test are performed to cover failures mechanisms in the component itself (die, package or die-package interface),
executed on the stand alone component
- Second level reliability focuses on the solder joint reliability, also known as board level reliability,
executed on dedicated daisy chains mounted to PCBs

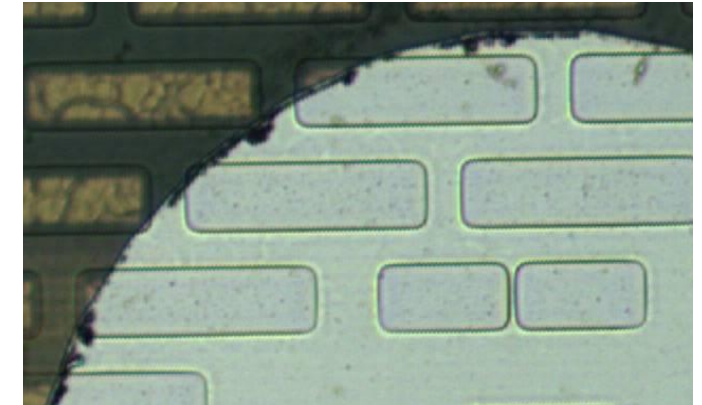


Case study: TC fails in WLCSP product

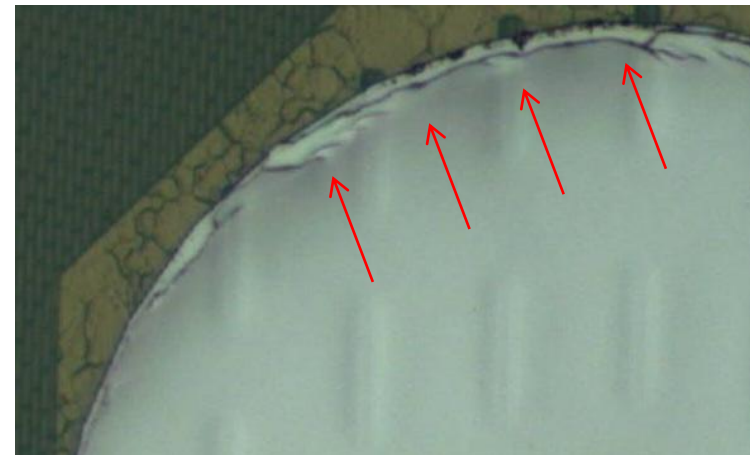
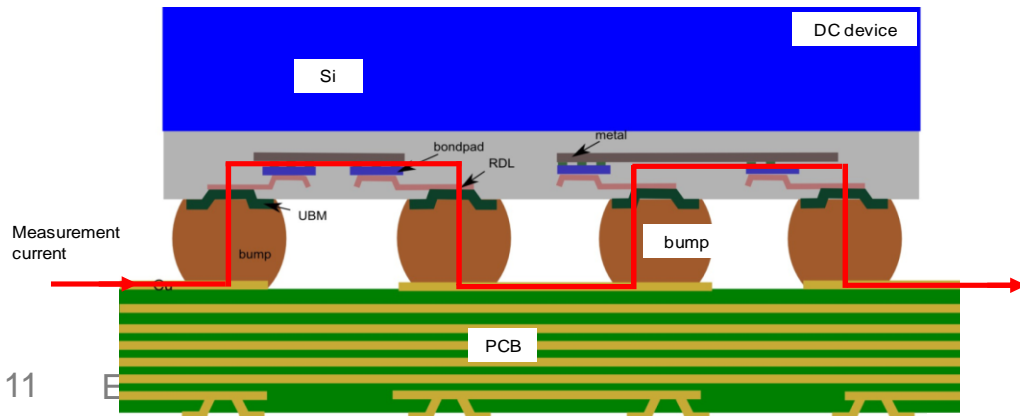
After 1st level TC on part of a wafer, Component Level (CL-TC):
No electrical failure and also no physical damage are observed



Visual inspection after bump removal:



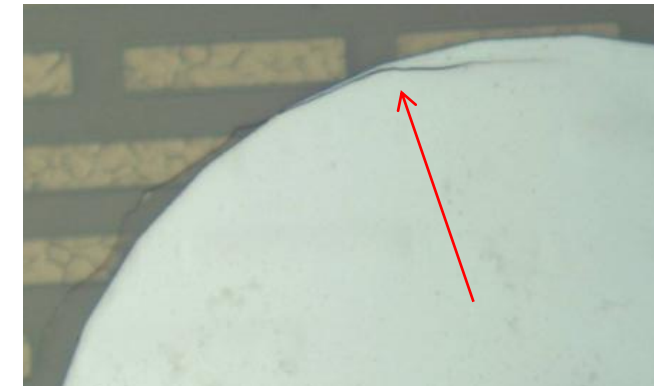
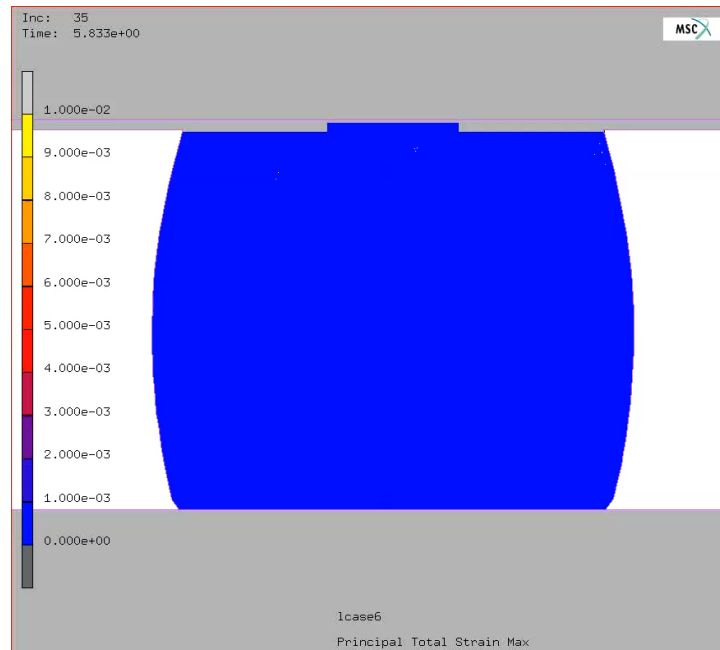
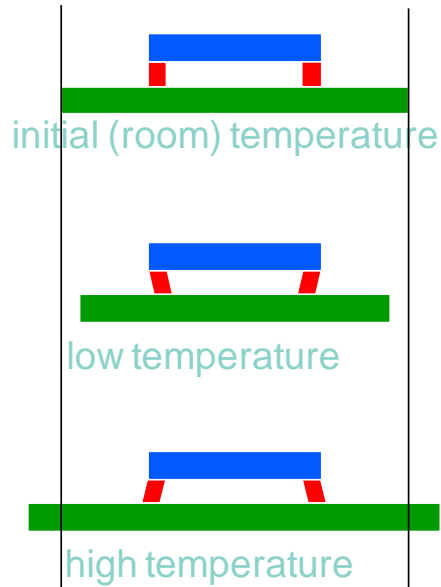
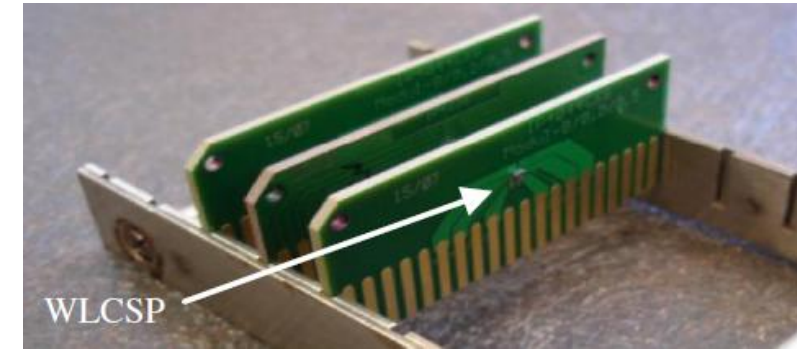
After 2nd level TC on daisy chains, Board Level (BL-TC):
No electrical failure but physical damage are observed



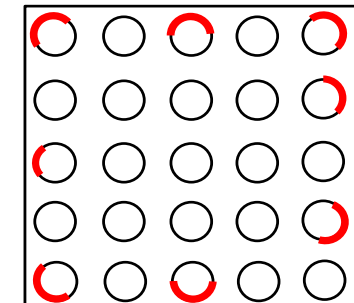
Case study: TC fails in WLCSP product

2nd level TC on actual devices, Application Level (AL-TC):

Electrical rejects because of physical damage are observed



Typical fail locations
(confirmed by FEM):



Test to fail and life time prediction

- Model: modified Coffin Manson

$$N_f = C_0 \times (\Delta T - \Delta T_0)^{-q}$$

- N_f : number of cycles to failure
- C_0 : material dependant constant
- ΔT : entire cycle range
- ΔT_0 : portion of the temperature range in the elastic region
- q : Coffin Manson exponent (failure mode dependent)

- Acceleration Factor (AF)

$$AF = \frac{N_{f, \text{stress}}}{N_{f, \text{use}}}$$

- $N_{f, \text{stress}}$: number of cycles to failure under stress conditions
- $N_{f, \text{use}}$: number of cycles to failure under use conditions (taken from Mission Profile)

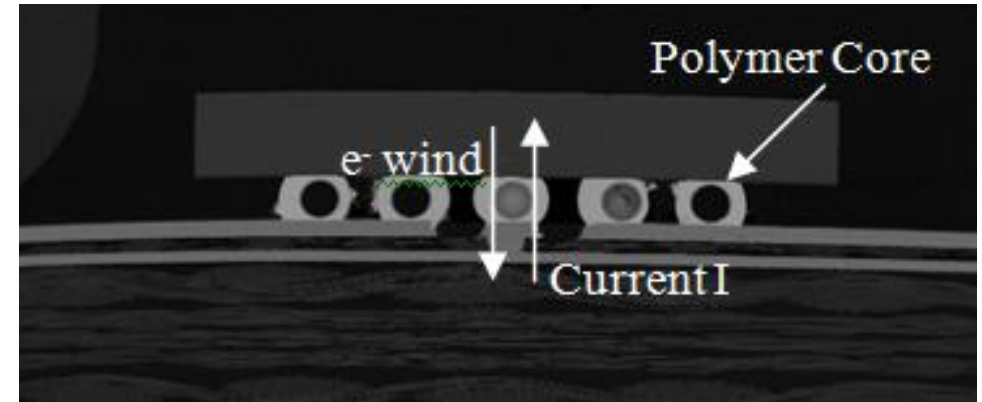
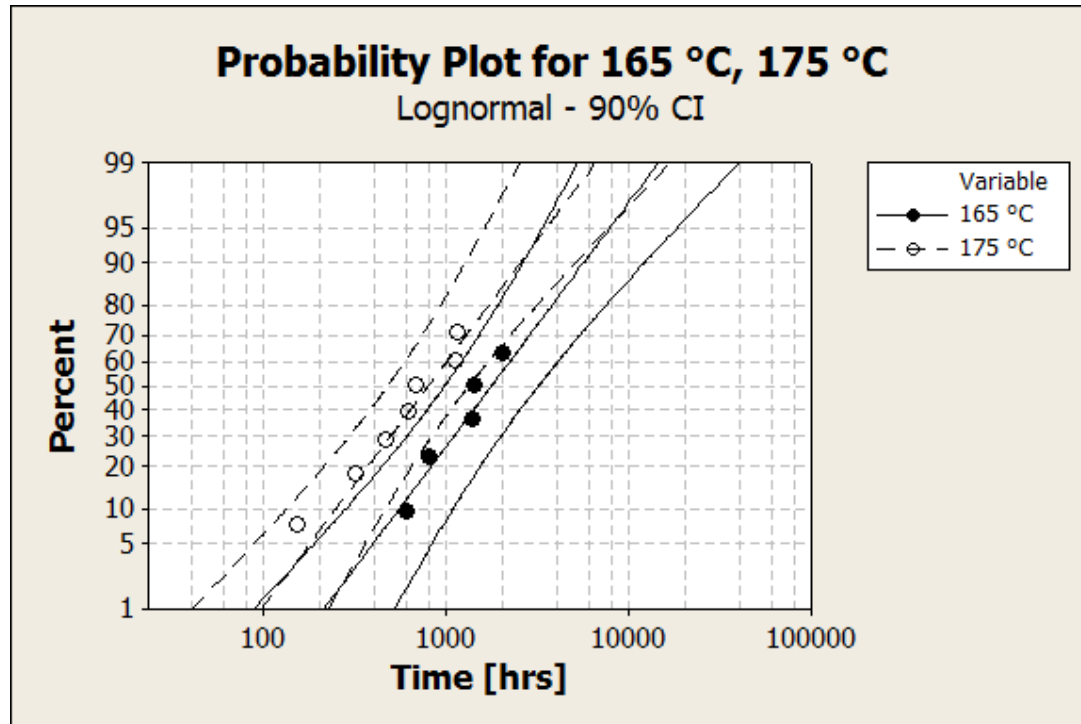
- Life time for a tablet or smart phone

- $q = 6$ (worst case value for a brittle fracture)
- $\Delta T - \Delta T_0 = 185$ (-40 to 125 °C)
- $N_{f, \text{stress}} = 100$ cls (experimental result)

$$\text{Life time} = 28 \text{ yrs}$$

Case study: Solder Joint Electromigration

- WLCSP test-structure



$$TTF = J^{-n} \times \exp\left(\frac{E_a}{kT}\right)$$

TTF: Time To Failure

J: current density

k: Boltzmann Constant

T: temperature

“n” and “E_a”: power exponent and activation energy (material specific)

Life time prediction

- Acceleration Factor (AF)

- $t_{50, \text{stress}}$: time 50 % of the population fails under stress conditions
 - $t_{50, \text{use}}$: time 50 % of the population fails under use conditions (taken from Mission Profile)

$$AF = \frac{t_{50, \text{stress}}}{t_{50, \text{use}}}$$

- Life time for a tablet or smart phone

- $E_a = 0.95 \text{ eV}$ (from results on previous slide)
 - Temperature under stress condition: 165 °C
 - Temperature under use condition: 85 °C

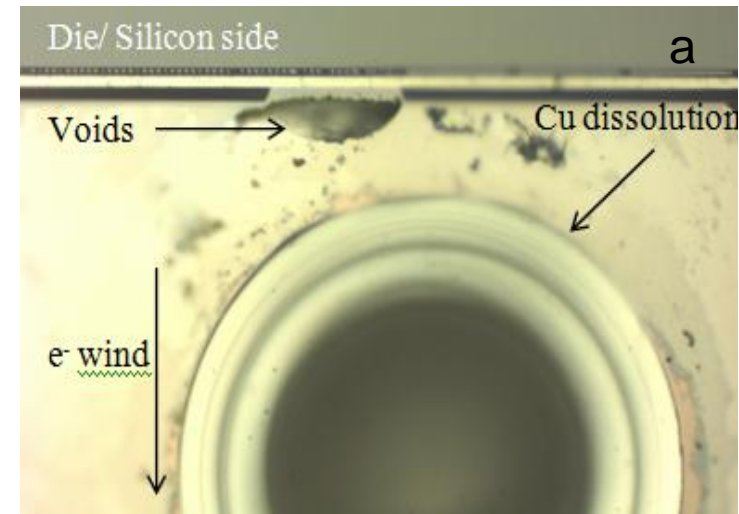
$$AF = 290$$

The expected lifetime for the application is **35 times** covered!

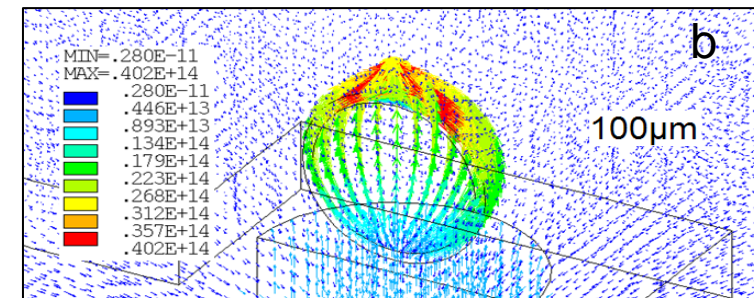
Understanding Preferred Failure Locations

- Weakest spots from

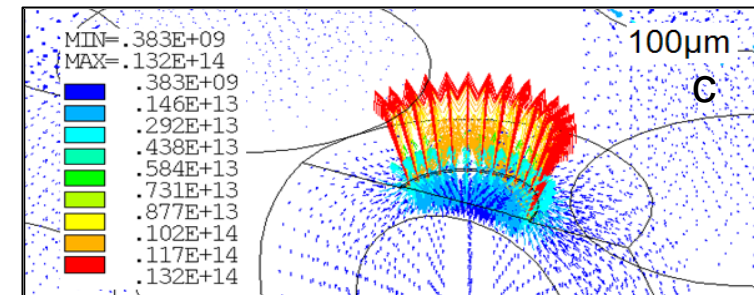
- a) X-section after EM test



- b) FEM Mass flux distribution in the copper shell around the polymer core



- c) FEM Mass flux distribution in the SnAg solder material



Conclusions

- For WL-CSPs, direct interaction between the PCB and the silicon/die via the solder joint is much larger than for products in conventional lead frame or substrate based technologies
- New test methods, like AL-TC, and detailed assessment of failure modes and mechanisms via FEM, both help to understand the impact of stress/loading in applications
- Life time under application conditions can be predicted when acceleration models are determined together with the acceleration parameters

Acknowledgment

- Co-authors: Rene Rongen, Romuald Roucou, Paul vd Wel, Frans Voogt, Frank Swartjes, Kirsten Weide-Zaage
- Other contributors: Jeroen Zaal for the modeling work, NXP Failure Analysis teams for the many X-sections and other sample preparations



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